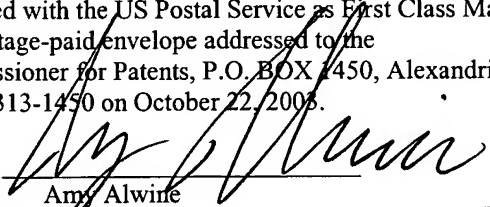


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<p>In re application of:</p> <p>Young et al.</p> <p>Serial No.: 10/614,311</p> <p>Filed: July 7, 2003</p> <p>Title: AVANCED BI-DIRECTIONAL LINEAR POLISHING SYSTEM AND METHOD</p>	<p>Group Art Unit: Not yet assigned Examiner: Not yet assigned Docket: NT-251C1-US</p> <p>CERTIFICATE OF MAILING</p> <p>I hereby certify that this correspondence is being deposited with the US Postal Service as First Class Mail in a postage-paid envelope addressed to the Commissioner for Patents, P.O. BOX 1450, Alexandria, VA 22313-1450 on October 22, 2003.</p> <p>Signed:  Amy Alwine</p>
---	--

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. BOX 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicants submit information herewith to comply with the obligations set forth in 37 CFR §1.56. This submission is not an admission that any of the documents are prior art or otherwise relevant to the subject application.

This IDS is submitted:

- ☐ with a filed patent application or within 3 months of the US application filing date;
- ☒ before the mailing of a first office action on the merits;
- ☐ after the first office action, but prior to a final rejection or notice of allowance, and is accompanied by the fee set forth in 37 CFR §1.17(p) or a certification set forth below; or
- ☐ after a final rejection or notice of allowance, and is accompanied by the fee set forth in 37 CFR §1.17(p) and a certification set forth below, where this submission is a petition requesting consideration of this IDS.

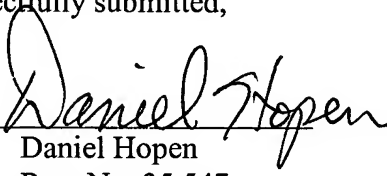
If identified above, Applicant certifies that:

- ☐ the information was first cited in a communication from a foreign patent office in a counterpart foreign application less than 3 months prior to this IDS; or

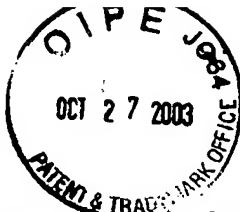
[] to the knowledge of the person signing this certification after making reasonable inquiry, the information was not known to any individuals designated in 37 CFR §1.56 more than 3 months prior to this IDS.

If any matters can be resolved by telephone, Applicant requests that the Patent and Trademark Office call the Applicant at the telephone number listed below.

Respectfully submitted,

By: 
Daniel Hopen
Reg. No. 35,547

NuTool, Inc.
Legal Department
1655 McCandless Drive
Milpitas, CA 95035
(408) 586-9500x268



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<p>In re application of:</p> <p>Young et al.</p> <p>Serial No.: 10/614,311</p> <p>Filed: July 7, 2003</p> <p>Title: AVANCED BI-DIRECTIONAL LINEAR POLISHING SYSTEM AND METHOD</p>	<p>Group Art Unit: Not yet assigned</p> <p>Examiner: Not yet assigned</p> <p>Docket: NT-251C1-US</p>
---	--

INFORMATION DISCLOSURE STATEMENT

US PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	
		669,923	Mar., 1901	Grauert	In Serial No. 09/684,059
		3,888,050	June, 1975	Elm	In Serial No. 09/684,059
		4,412,400	Nov., 1983	Hammond	In Serial No. 09/684,059
		4,802,309	Feb., 1989	Heynacher	In Serial No. 09/684,059
		5,245,796	Sep., 1993	Miller et al.	In Serial No. 09/684,059
		5,335,453	Aug., 1994	Baldy et al.	In Serial No. 09/684,059
		5,377,452	Jan., 1995	Yamaguchi	In Serial No. 09/684,059
		5,377,453	Jan., 1995	Pernecky	In Serial No. 09/684,059
		5,429,733	July, 1995	Ishida	In Serial No. 09/684,059
		5,489,235	Feb., 1996	Gagliardi et al.	In Serial No. 09/684,059
		5,558,568	Sep., 1996	Talieh et al.	In Serial No. 09/684,059
		5,593,344	Jan., 1997	Weldon et al.	In Serial No. 09/684,059
		5,650,039	July, 1997	Talieh	In Serial No. 09/684,059
		5,679,212	Oct., 1997	Kato et al.	In Serial No. 09/684,059
		5,692,947	Dec., 1997	Talieh et al.	In Serial No. 09/684,059
		5,707,409	Jan., 1998	Martin et al.	In Serial No. 09/684,059
		5,759,918	June, 1998	Hoshizaki et al.	In Serial No. 09/684,059
		5,762,751	June, 1998	Bleck et al.	In Serial No. 09/201,928
		5,770,521	June, 1998	Pollock	In Serial No. 09/201,928
		5,807,165	Sep., 1998	Uzoh et al.	In Serial No. 09/201,928
		5,810,964	Sep., 1998	Shiraishi	In Serial No. 09/684,059
		5,851,136	Dec., 1998	Lee	In Serial No. 09/684,059
		5,893,755	April, 1999	Nakayoshi	In Serial No. 09/684,059
		5,899,798	May, 1999	Trojan et al.	In Serial No. 09/684,059
		5,899,801	May, 1999	Trolles et al.	In Serial No. 09/684,059
		5,908,530	June, 1999	Hoshizak et al.	In Serial No. 09/684,059
		5,913,716	June, 1999	Mucci et al.	In Serial No. 09/684,059
		5,951,368	Sep., 1999	Watanabe et al.	In Serial No. 09/684,059
		5,951,377	Sep., 1999	Vaughn et al.	In Serial No. 09/684,059
		5,961,372	Oct., 1999	Shendon	In Serial No. 09/684,059
		5,975,988	Nov., 1999	Christianson	In Serial No. 09/684,059

	6,017,831	Jan., 2000	Beardsley et al.	In Serial No. 09/684,059
	6,068,542	May, 2000	Hosokai	In Serial No. 10/126,469
	6,110,025	Aug., 2000	Williams et al.	In Serial No. 10/126,469
	6,113,479	Sep., 2000	Sinclair et al.	In Serial No. 10/126,469
	6,129,540	Oct., 2000	Hoopman et al.	In Serial No. 10/126,469
	6,135,859	Oct., 2000	Tietz	In Serial No. 10/126,469
	6,136,715	Oct., 2000	Shendon et al.	In Serial No. 10/126,469
	6,179,690	Jan., 2001	Talieh	In Serial No. 10/126,469
	6,179,709	Jan., 2001	Redeker et al.	In Serial No. 10/126,469
	6,207,572	Mar., 2001	Talieh	In Serial No. 09/684,059
	6,241,583	June, 2001	White	In Serial No. 10/126,469
	6,302,767	Oct., 2001	Tietz	In Serial No. 10/126,469
	6,312,319	Nov., 2001	Donohue et al.	In Serial No. 10/126,469
	6,379,231	April, 2002	Birang et al.	In Serial No. 10/126,469
	6,413,873	July, 2002	Li et al.	In Serial No. 10/126,469
	6,419,559	July, 2002	Gurusamy et al.	In Serial No. 10/252,149
	6,428,394	Aug., 2002	Mooring et al.	In Serial No. 10/252,149
	6,439,978	Aug., 2002	Jones et al.	In Serial No. 10/252,149
	6,468,139	Oct., 2002	Talieh et al.	In Serial No. 10/252,149
	6,475,070	Nov., 2002	White	In Serial No. 10/252,149
	6,500,056	Dec., 2002	Krusell et al.	In Serial No. 10/252,149

FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant		
		DE 31 13 204	Oct., 1982	Lambelet	In Serial No. 09/684,059	
		EP 0 517 594	Dec., 1992	Baldy	In Serial No. 09/684,059	
		WO 97 20660	June, 1997	Shendon	In Serial No. 09/684,059	
		WO 98/45090	Oct., 1998	Donhue et al.	In Serial No. 09/684,059	
		WO 99/22908	May, 1999	Sommer	In Serial No. 09/684,059	
		EP 0 941 806 A2	Sep., 1999	Jew et al.	In Serial No. 09/684,059	
		WO 00/32356	June, 2000	Talieh	In Serial No. 09/684,059	
		EP 1 025 955 A2	Aug., 2000	Somekh et al.	In Serial No. 09/684,059	
		WO 02/02272 A1	Jan., 2002	Owczarz et al.	In Serial No. 09/684,059	

OTHER DOCUMENTS

Examiner Initials	Cite No.			Translation
		J.M. Steigerwald, et al., "Pattern Geometry Effects in the Chemical-Mechanical Polishing of Inlaid Copper Structures", Oct. 1994, pp. 2842-2848.	In Serial No. 09/576,064	

Examiner Signature		Date Considered	
--------------------	--	-----------------	--